

## TRANSMITTAL

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<b>Title of Invention</b>	HIGH PRESSURE PROCESSING CHAMBER FOR SEMICONDUCTOR SUBSTRATE
Application Number :	09/912844 
Date :	2001-07-24
First Named Applicant:	Biberger Maximilian A.
Confirmation Number:	5915
Attorney Docket Number:	

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<b>Documents being submitted:</b>	<b>Files</b>
us-ids	SSI00501-usidst.xml us-ids.dtd us-ids.xsl
<b>Comments</b>	